

5-2151 Policy

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December 21st, 1959

COCOM Document No. 3713.60/2

COORDINATING COMMITTEE

RECORD OF DISCUSSION

ON

ITEM 1360 - EQUIPMENT SPECIALLY DESIGNED FOR PURIFYING  
AND PROCESSING SILICON AND GERMANIUM

November 30th and December 18th, 1959

Present: Belgium (Luxembourg), Canada, France, Germany, Italy, Japan,  
Netherlands, United Kingdom, United States.

References: COCOM Documents Nos. 3715.00/1, 1959 Review W.P.4 and W.P.4/1360,  
3713.60/1.

1. On the 30th November the JAPANESE Delegate confirmed the agreement previously given ad referendum to the definition shown in paragraph 1 of COCOM Document No. 3713.60/1.

2. On the 18th December the FRENCH and ITALIAN Delegations similarly confirmed their ad referendum agreement.

CONCLUSION: The COMMITTEE noted that Item 1360 would be changed to read as follows:

"Equipment for the manufacture of semi-conductor materials as follows:

- (a) Equipment specially designed for the production or processing of dendritic forms of any semi-conductor material, or combination thereof, suitable for use in diodes or transistors;
- (b) Equipment n.e.s., specially designed for purifying and processing silicon and germanium except equipment designed for the zone purification of germanium.

NOTE: The term "dendritic" signifies a ribbon-like product of semi-conductor material which may be drawn in various widths, thicknesses and lengths and which may represent processing stages from a relatively pure form of the material through advanced stages of treatment."

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